# Supplementary information

## **3D** Printing-Based Cellular Microelectrodes for High-Performance

### Asymmetric Quasi-Solid-State Micro-Pseudocapacitors

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#### Calculation of Microelectrode and Device Capacitance and Energy Density Values

According to the obtained CV curves, the areal microelectrode (or device) capacitance values ( $C_a$ ) of are calculated as follows:

$$C_a = \frac{\int i dV}{2u \cdot \Delta V \cdot S} \tag{S1}$$

where *i* is the charge and discharge current values, *u* represents the scan rates, *V* represents the corresponding voltage values,  $\Delta V$  and *S* are the corresponding voltage window and the total area, respectively.

The capacities  $(Q_a)$  of microelectrodes (or devices) were calculated by the following equation:

$$Q_a = C_a \cdot \Delta V \tag{S2}$$

where  $C_a$  is the corresponding capacitance,  $\Delta V$  is the potential window.

According to the obtained device capacitance values ( $C_a$ ), the device areal energy density values ( $E_a$ ) are calculated as follows:

$$E_a = \frac{C_a \cdot \left(\Delta V\right)^2}{7200} \tag{S3}$$

where  $C_a$  and  $\Delta V$  represent the device capacitance value and voltage window, respectively.

According to the obtained GCD curves, the areal microelectrode (or device) capacitance values ( $C_a$ ) of are calculated as follows:

$$C_a = \frac{I \cdot \Delta t}{S \cdot \Delta V} \tag{S4}$$

where I represents the discharge current values,  $\Delta t$  is the discharge time,  $\Delta V$  and S are the corresponding voltage window and the total area, respectively.



**Fig. S1** (a) Apparent viscosities as a function of shear rate for GO ink. (b) Storage modulus and loss modulus values as a function of shear stress.<sup>1</sup>



Fig. S2 SEM images of 3D-printed interdigitated (a) 3DG framework and (b) PG.



**Fig. S3** (a) XRD patterns of fabricated samples and (b-d) simulated PXRD patterns for (b) rGO, (c) NC-3DG and (d) M-3DG.



Fig. S4 Raman spectra of NC-3DG and M-3DG microelectrodes.



**Fig. S5** TEM images of (a) NC-3DG and (b) M-3DG. The insets in (a,b) are corresponding SAED patterns (scale bar: 2 1/nm). (c,d) EDS spectra of (c) NC-3DG and (d) M-3DG obtained from the sample shown in (a) and (b), respectively.



**Fig. S6** (a) XPS survey spectrum of NC-3DG. (b) C 1s, (c) Ni 2p and (d) Co 2p XPS spectra on NC-3DG.



**Fig. S7** (a) XPS survey spectrum of M-3DG. (b) Mn 2p, (c) C 1s and (d) O 1s XPS spectra on M-3DG.



Fig. S8 CV curves at a scan rate of 50 mV s<sup>-1</sup> for 3DG obtained at different reduction temperatures.



**Fig. S9** CV curves of and corresponding capacitance values of (a,b) NC-3DG(2) and (c,d) M-3DG microelectrodes.



**Fig. S10** CV curves at a scan rate of 10 mV s<sup>-1</sup> for asymmetric NC-3DG//M-3DG MPC and current collector.



Fig. S11 (a-c) SEM images of NC-3DG microelectrodes with different Ni/Co mole ratios.

Device Electrodes	Specific capacity (rate)	Electrolyte	Ref.
3D-printing-stamped Ti <sub>3</sub> C <sub>2</sub> T <sub>x</sub>	37 mC cm <sup>-2</sup> (0.025 mA cm <sup>-2</sup> )	H <sub>2</sub> SO <sub>4</sub> /PVA	2
3D-printed rGO	74 mC cm <sup>-2</sup> (5 mV s <sup>-1</sup> )	H <sub>2</sub> SO <sub>4</sub> /PVA	3
3D-printed GO/PANI	123 mC cm <sup>-2</sup> (5 mV s <sup>-1</sup> )	H <sub>3</sub> PO <sub>4</sub> /PVA	4
VO <sub>x</sub> /rGO//G-VNQDs/rGO	333 mC cm <sup>-2</sup> (0.63mA cm <sup>-2</sup> )	LiCl/PVA	5
NC-3DG//M-3DG	500 mC cm <sup>-2</sup> (2 mV s <sup>-1</sup> )	KOH/PVA	This work

 Table S1 A review of capacitive performance of reported MSCs.

### References

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